



PTO/SB/08A (08-03)

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Substitute for form 1449/PTO

Complete If Known

Application Number	10/616,662
Filing Date	July 10, 2003
First Named Inventor	Zhang, et al.
Art Unit	1751
Examiner Name	

Sheet	1	of	1	Attorney Docket Number	06293P2 USA
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U. S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
rr	US- 6,261,745	07-17-2001	Komano Hiroshi, et al.		
rr	US- 5,977,041	11-02-1999	Honda Kenji		
rr	US- 5,756,267	05-26-1998	Kobayashi Kesanao, et al.		
rr	US- 5,650,543	07-22-1997	Medina Steven Wayne		
rr	US- 4,833,067	05-23-1989	Asaumi Shingo, et al.		
rr	US- 2002/016272	02-07-2002	Kakizawa Masahiko, et al.		
	US-				

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³ Number ⁴ Kind Code ⁵ (if known)				
rr	EP 1 115 035 A	07-11-2001	Air Products and Chemicals, Inc.			✓
rr	EP 1 389 745 A	02-18-2004	Air Products and Chemicals, Inc.			✓

Examiner Signature		Date Considered	9/3/2005
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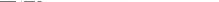
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<p>Substitute for form 1449/PTO</p> <p>INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(Use as many sheets as necessary)</i></p>				<p>Complete if Known</p>	
				Application Number	10/61,662 10 616 662
				Filing Date	July 10, 2003
				First Named Inventor	Zhang, et al.
				Art Unit	1751
				Examiner Name	
Sheet	1	of	1	Attorney Docket Number	06293P2 USA

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Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³ Number ⁴ Kind Code ^{5/6} (known)	MM-DD-YYYY			
M	JP2004184648A		07-02-2004	Kobayashi Masakazu		✓
M	WO 2004/051379		06-17-2004	Clariant Int'l Ltd.		

Examiner Signature		Date Considered	9/3/2005
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<p>Substitute for form 1449/PTO</p> <p>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</p> <p><i>(Use as many sheets as necessary)</i></p>				Complete if Known	
				Application Number	10/616,662
				Filing Date	10 July 2003
				First Named Inventor	Peng Zhang, et al.
				Art Unit	1751
				Examiner Name	
Sheet	1	of	1	Attorney Docket Number	06293P2 USA

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Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³ Number ⁴ Kind Code ^{5,6} (known)				

Examiner Signature		Date Considered	9/3/2005
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7/10/03 ✓

Sheet 1 of 1

FORM PTO-1449 (Modified)	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY.DOCKET NO. 06293P2 USA	SERIAL NO.
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)		APPLICANT Peng Zhang, et al.	
		FILING DATE	GROUP
(37 CFR 1.98(b))			

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS								COUNTRY	CLASS	SUBCLASS	TRANSLATION	
		DOCUMENT NUMBER				DATE	YES	NO				
✓	EP	1	1	1	5	0	3	5	Europe			X
✓	JP	95	1	4	2	3	4	9	Japan			X
✓	JP	96	0	0	8	1	6	3	Japan			X
✓	WO	0	0	0	3	3	0	6	World			X
✓	WO	0	2	2	3	5	9	8	World			X
✓	WO	8	7	0	3	3	8	7	World			X
✓	WO	9	9	1	5	6	0	9	World			X
✓	WO	9	9	6	0	0	8	3	World			X
✓	WO	9	9	6	0	4	4	8	World			X

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

✓ Domke, W. D., et al., "Pattern Collapse in High Aspect Ratio DUV and 193nm Resists," Proc. SPIE-Int. Soc. Opt. Eng. 3999, 313-321, 2000.

✓ Cheung, C., et al., "A Study of a Single Closed Contact for 0.18 Micron Photolithography Process," Proc. SPIE-Int. Soc. Opt. Eng. 3998, 738-741, 2000.

✓ S. Hien, et al., "Collapse behavior of single layer 193 and 157 nm resists: Use of surfactants in the rinse to realize the sub 130 nm nodes," Infineon Technologies, International SEMATECH, Center for Nano Technology, University of Wisconsin.

✓ T. Tanaka, et al., "Mechanism of Resist Pattern Collapse During Development Process," Jpn. J. Appl. Phys. Vol. 32 (1993), pp. 6059-6064, Part 1, No. 12B.

EXAMINER

DATE CONSIDERED

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